

ABSTRACT OF THE DISCLOSURE

Disclosed is a fabricating system including a plurality of processing apparatuses connected to each other by means of an inter-apparatus transporter, wherein one group of semiconductor wafers are processed in processing apparatuses and other group of wafers are transported to specified processing apparatuses for a time interval from (T_0+T) to a time T_0 ; and another group of wafers are processed and the remaining group of wafers are transported for a time interval from (T_0+T) to (T_0+2T) . Since processing apparatuses can receive at least one of works from the inter-apparatus transporter for a time interval T_{\min} , the distribution of works from the transporter to processing apparatuses is completed for the time interval T_{\min} . The transporter is emptied for each time interval T_{\min} , and works are unloaded to the emptied transporter, which makes easy the scheduling, control and management of the transporting of a plurality of works in the fabricating system. Moreover, since the fabricating system including processing apparatuses is periodically controlled at a cycle time T_{\min} , the scheduling of a plurality of works can be made easy, to enhance the level of optimization, thus improving the productivity.